



Attorney Docket No.: SAM-0256  
Application Serial No.: 09/993,832  
Reply to Office Action of: Sept. 22, 2004

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s):	Sung-Un Kwean, <i>et al.</i>	Examiner: Ume Eromini, Lynette T.
Serial No.:	09/993,832	Group Art Unit: 1765
Filing Date:	November 6, 2001	
Title:	ETCHING GAS COMPOSITION OF SILICON OXIDE AND METHOD OF ETCHING SILICON OXIDE USING THE SAME	

CERTIFICATE OF MAILING UNDER 37 C.F.R. 1.8

I hereby certify that this correspondence is being deposited with the United States Post Office as First Class Mail on the date indicated below in an envelope addressed to Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

11-17-04  
Date

Vanessa Marakas  
Vanessa Marakas

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Enter Amendment  
12/11/2004

RESPONSE

Sir:

The following is in response to the Office Action dated September 22, 2004.

Remarks/Arguments begin on page 2 of this paper.